

03500.012083.2

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Keiko CHIBA et al.	: Previous Examiner: H. K. Song
)
	: Previous Group Art Unit: 2882
Application No.: Divisional of Application No.)
09/970,826, filed October 5, 2001	:
)
Filed: December 17, 2003	:
)
For: REFLECTION TYPE MASK (As Amended)	: December 17, 2003

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to examination on the merits, please amend the above-identified application as follows:

IN THE TITLE:

Please cancel the current title and insert the following:

~~X-RAY MASK, AND EXPOSURE APPARATUS AND METHOD USING THE SAME~~

-- REFLECTION TYPE MASK --.